APPARATUS AND METHOD FOR DETECTING WAFER POSITION

Inventor: CHEN, Jun-Ming et al. Docket No. 4425-308

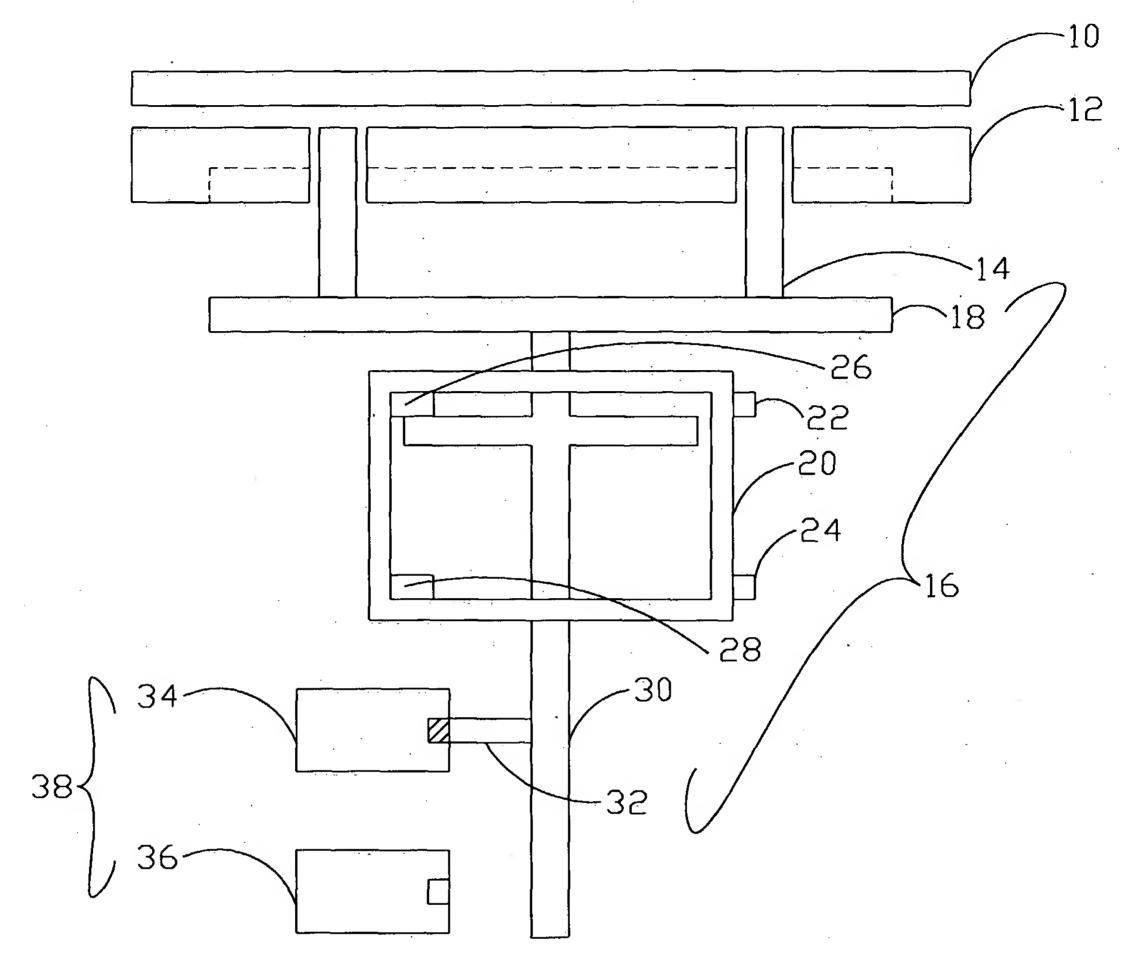


FIG.1A(Prior Art)

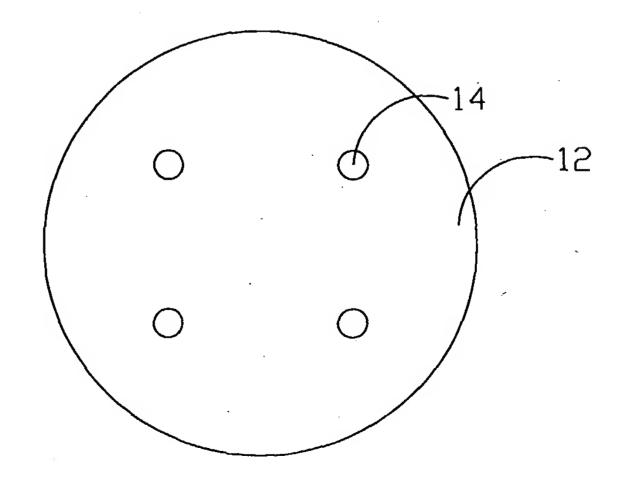


FIG.1B(Prior Art)

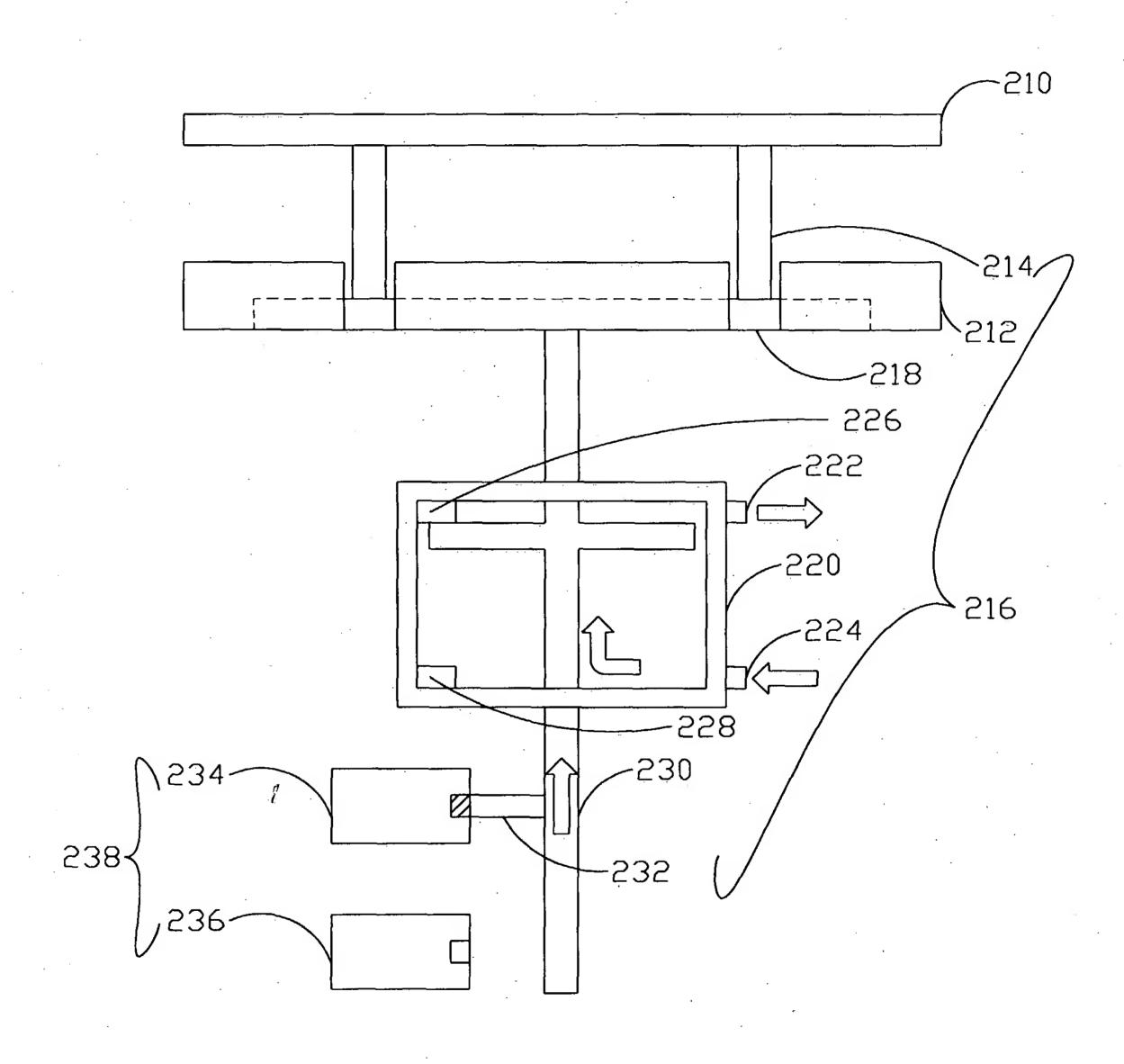


FIG.2A(Prior Art)

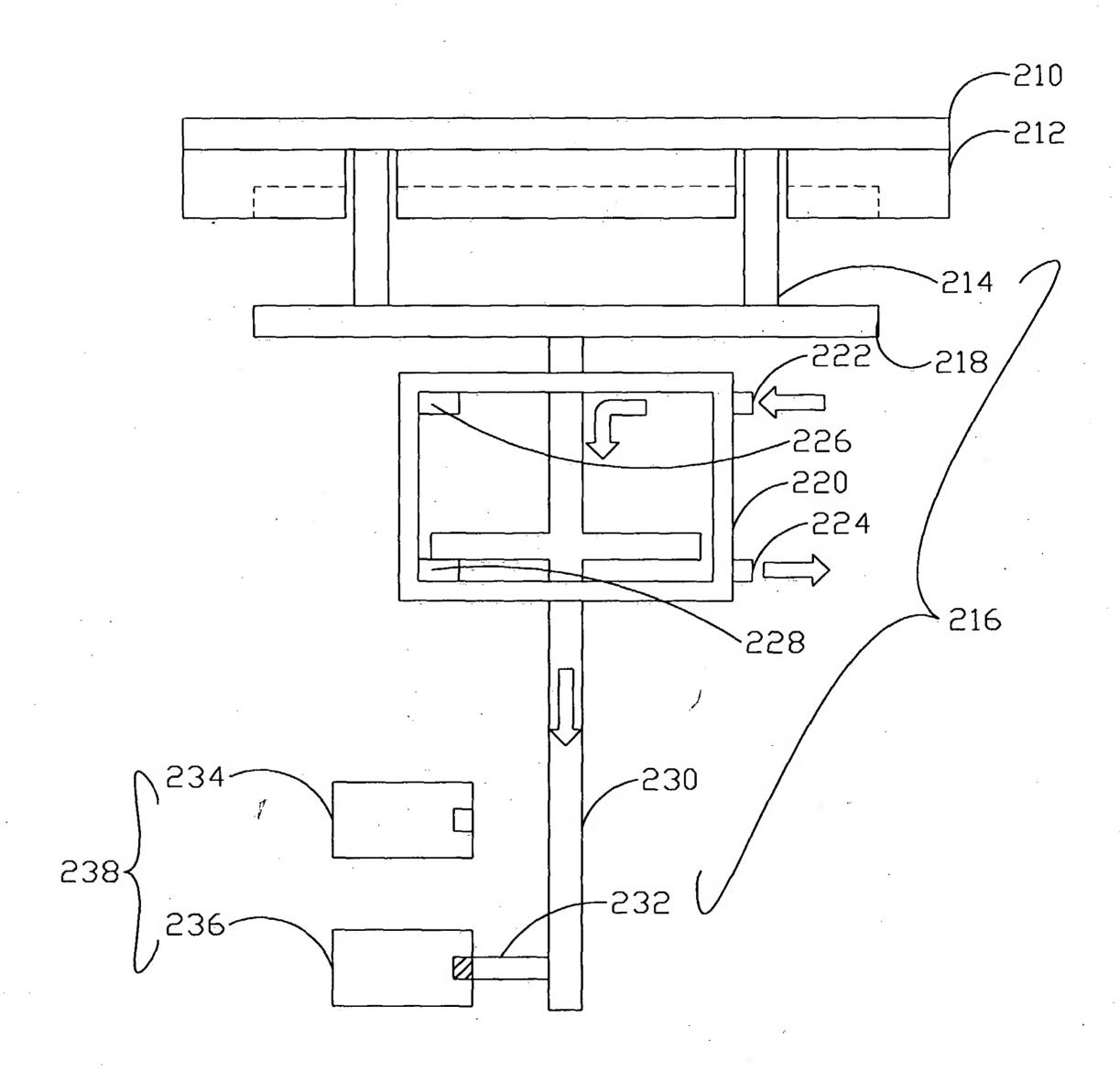


FIG.2B(Prior Art)

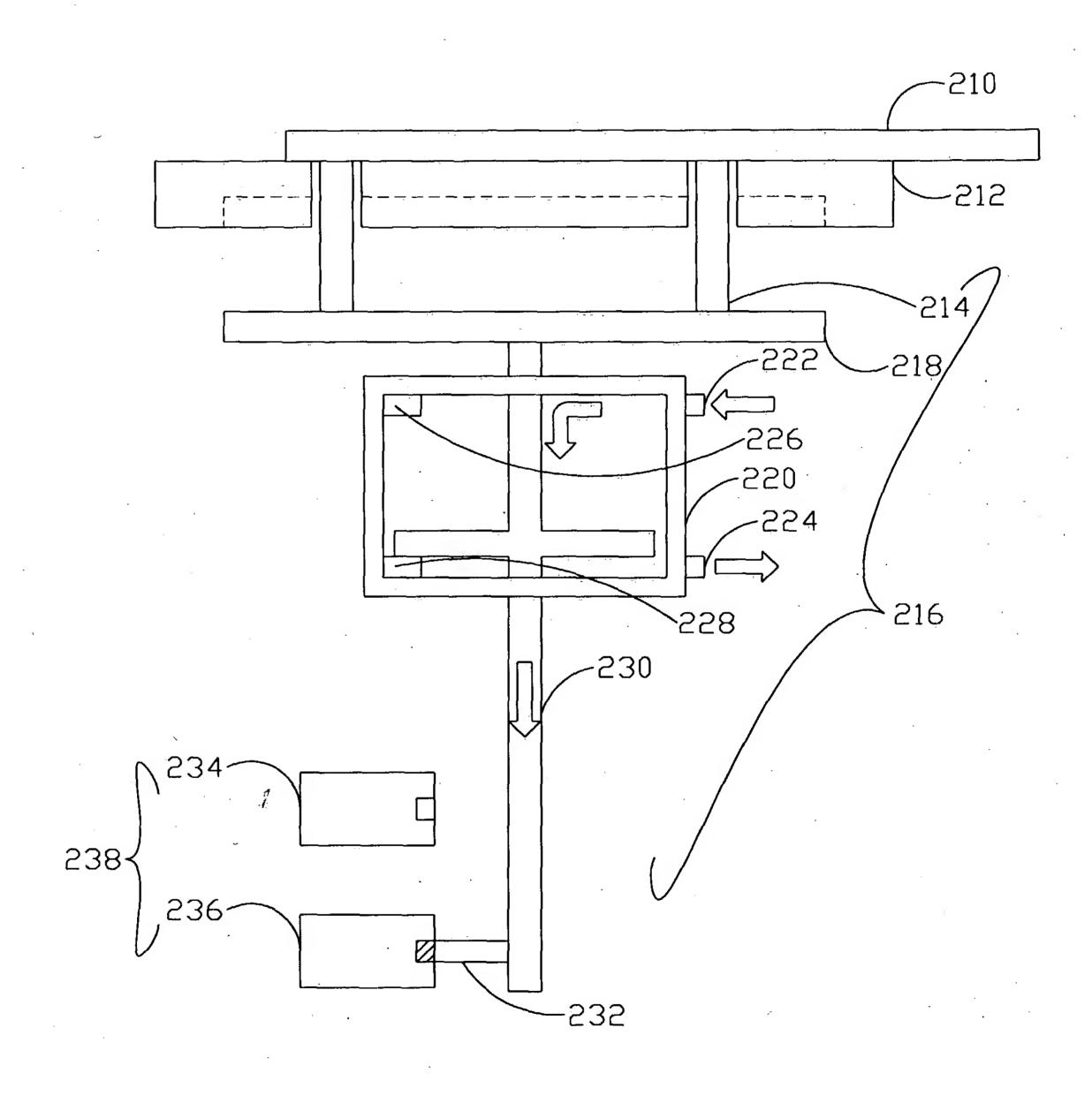


FIG.2C(Prior Art)

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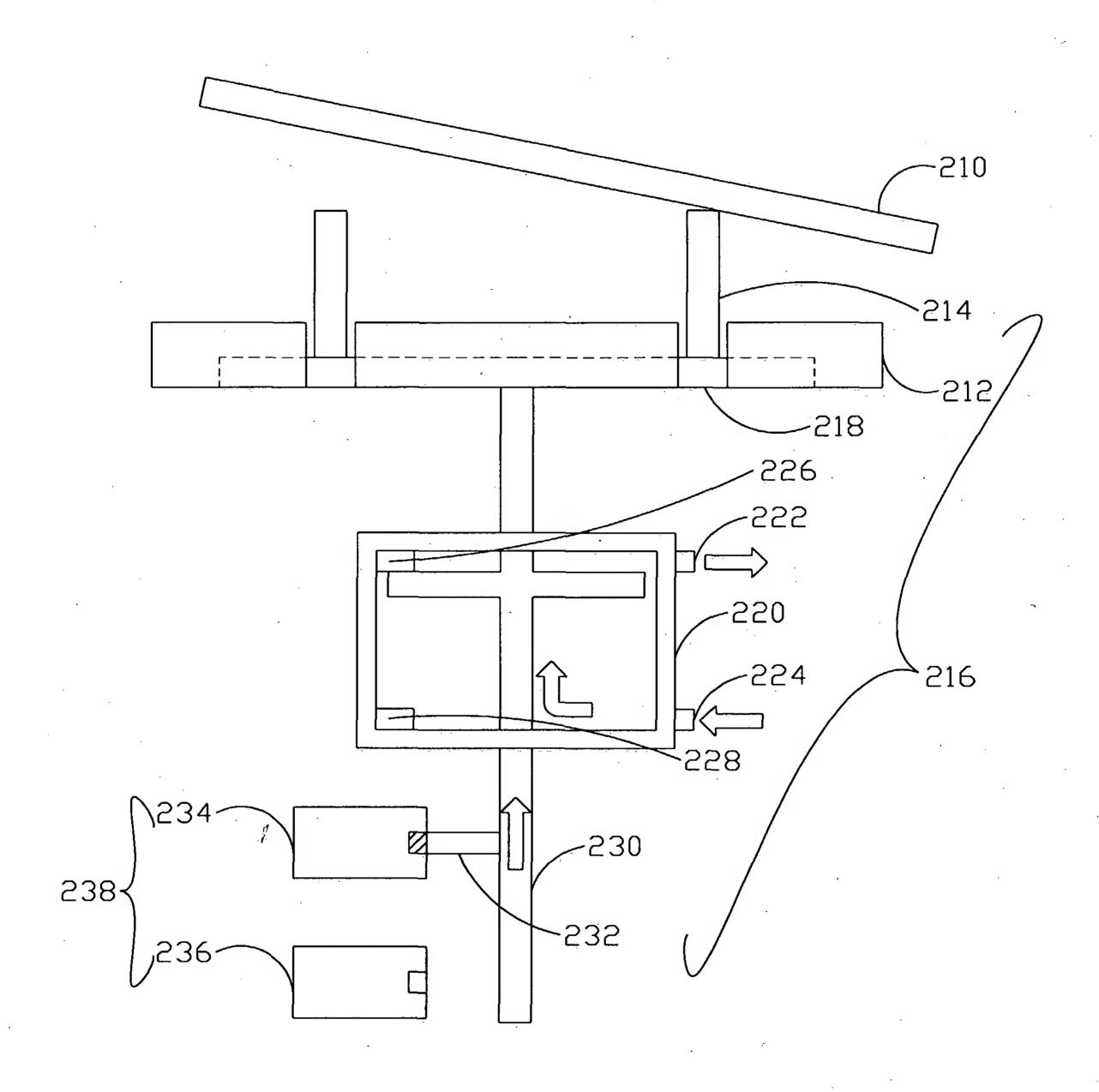


FIG.2D(Prior Art)

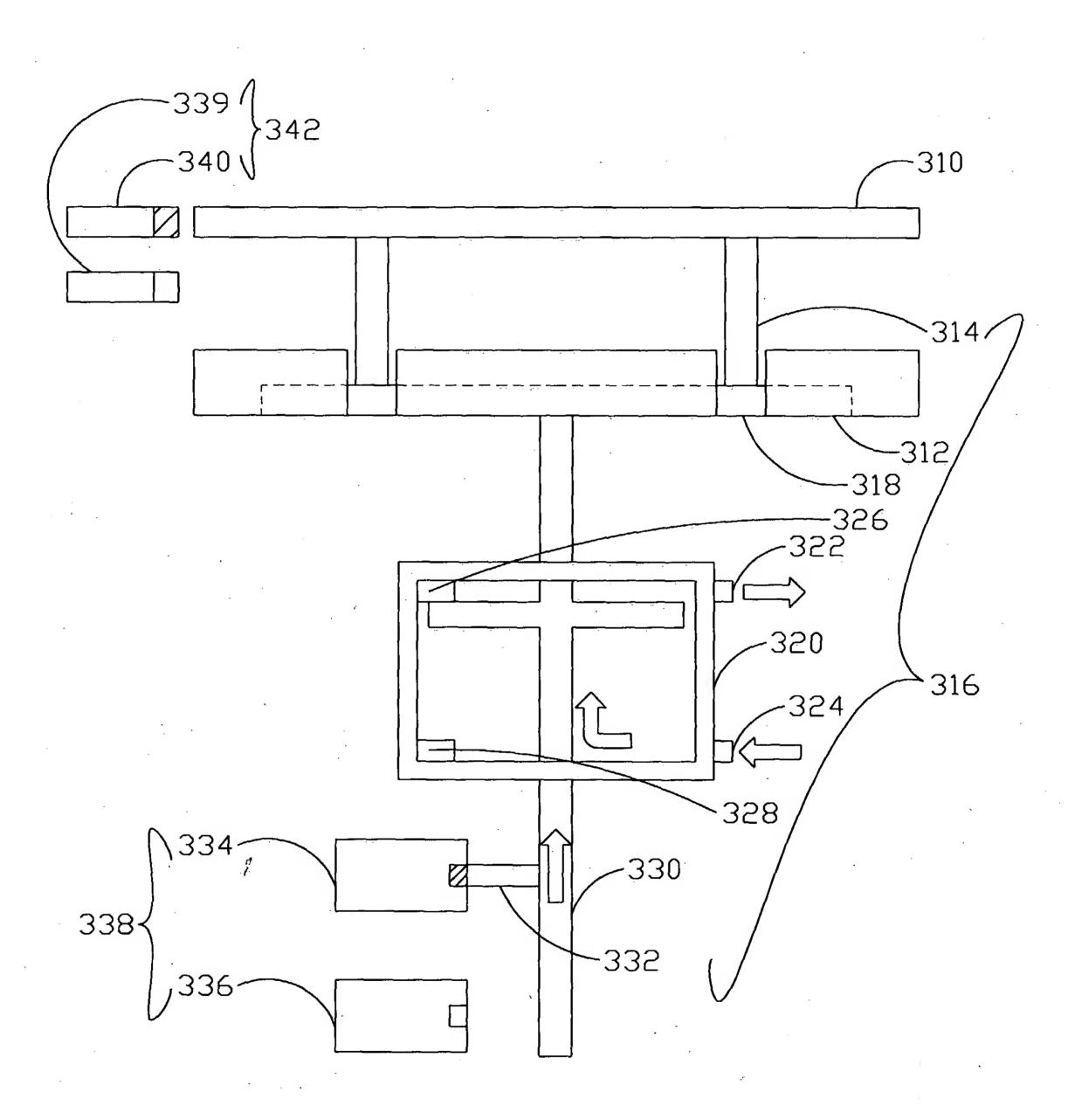


FIG.3A

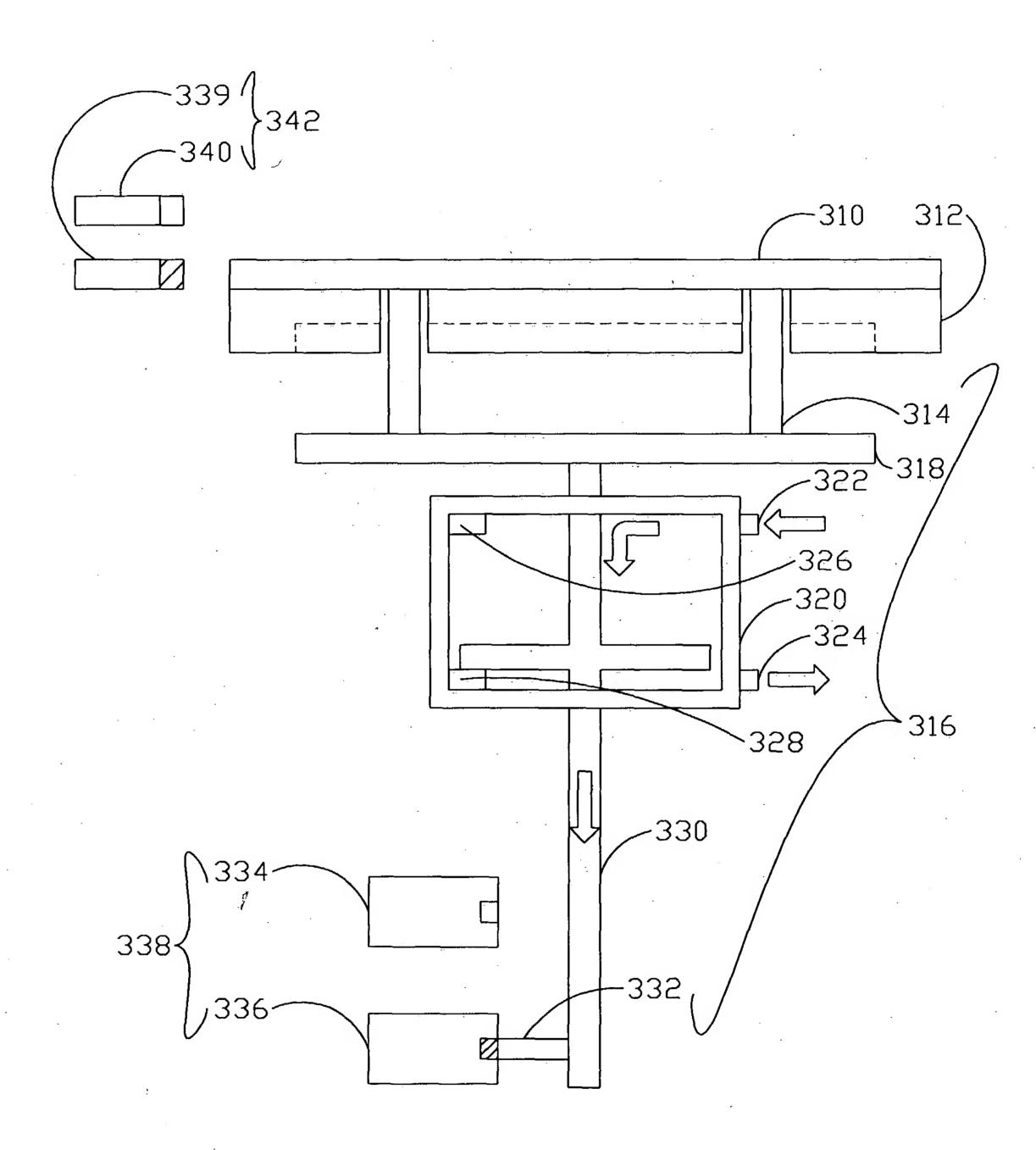


FIG.3B

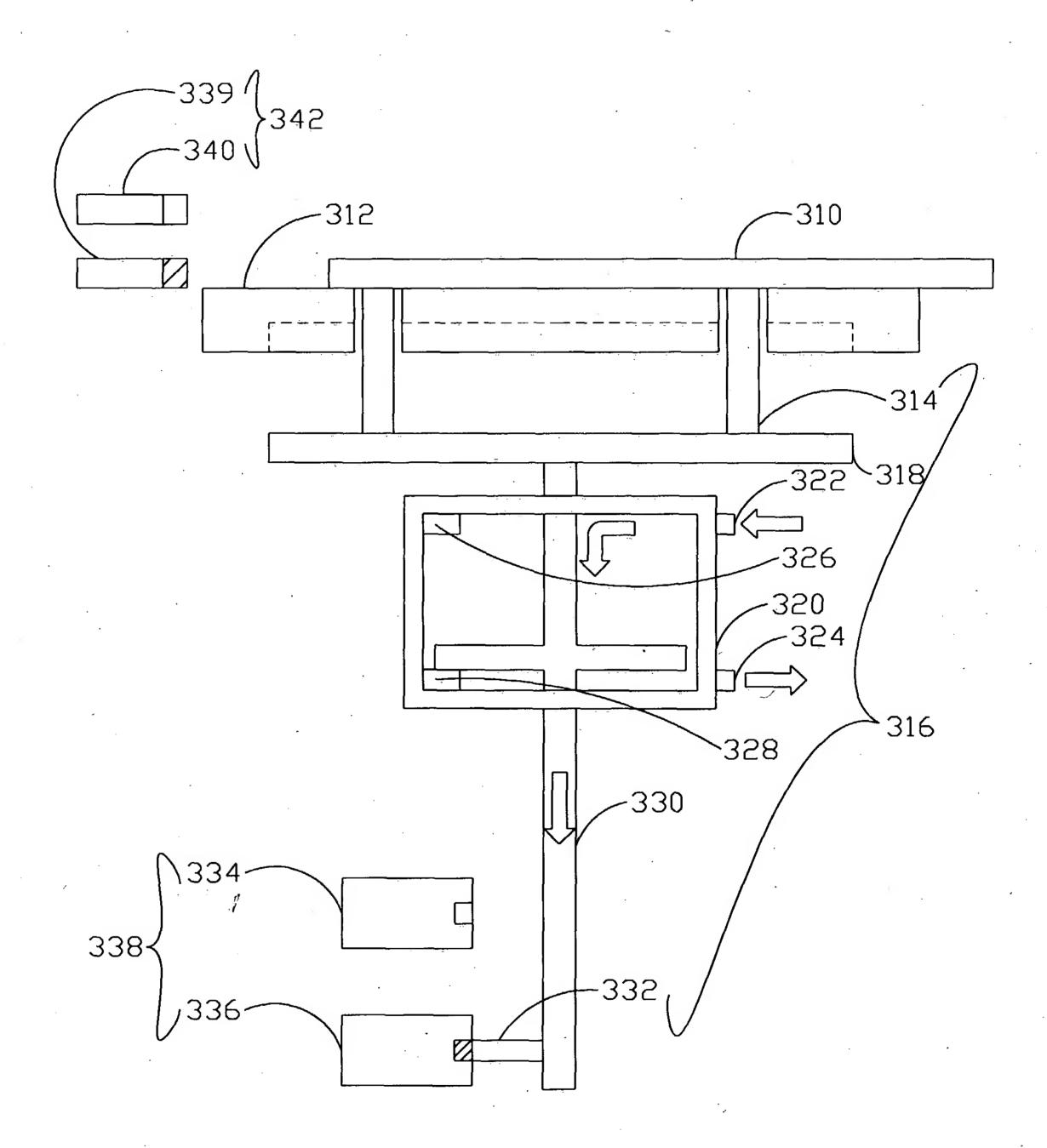


FIG.3C

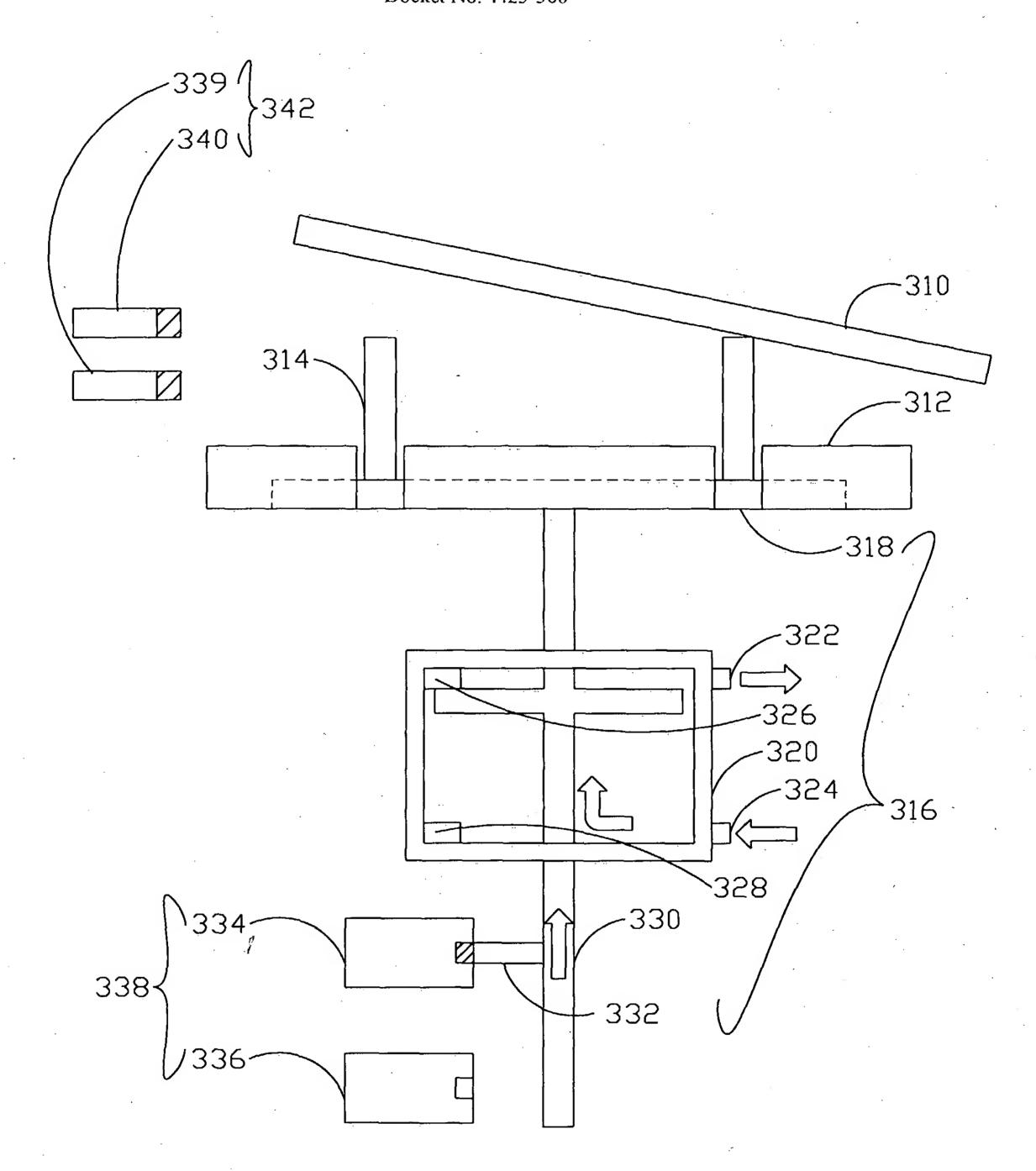


FIG.3D

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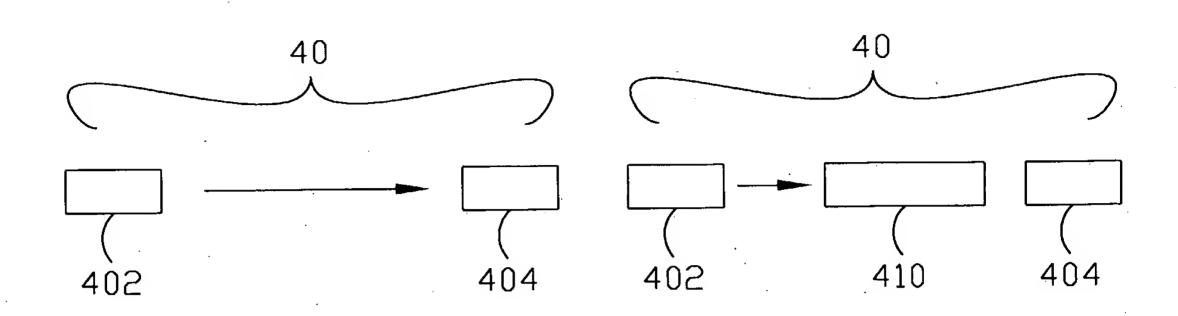


FIG.4A

FIG.4B

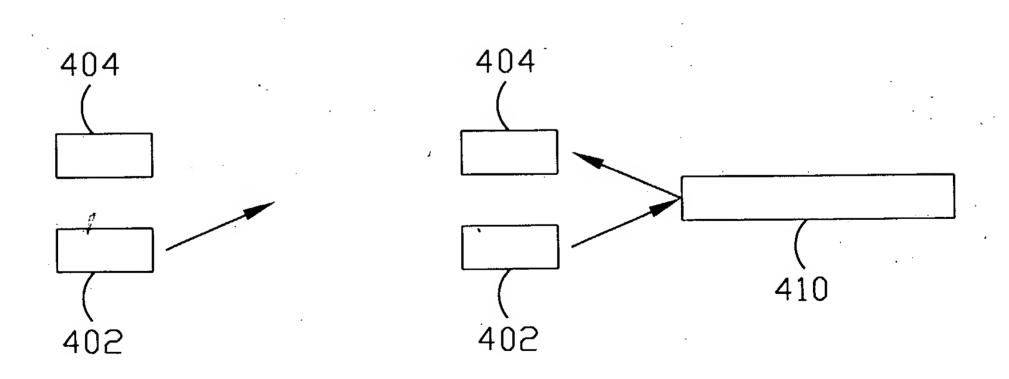


FIG.4C

APPARATUS AND METHOD FOR DETECTING WAFER POSITION Inventor: CHEN, Jun-Ming et al.

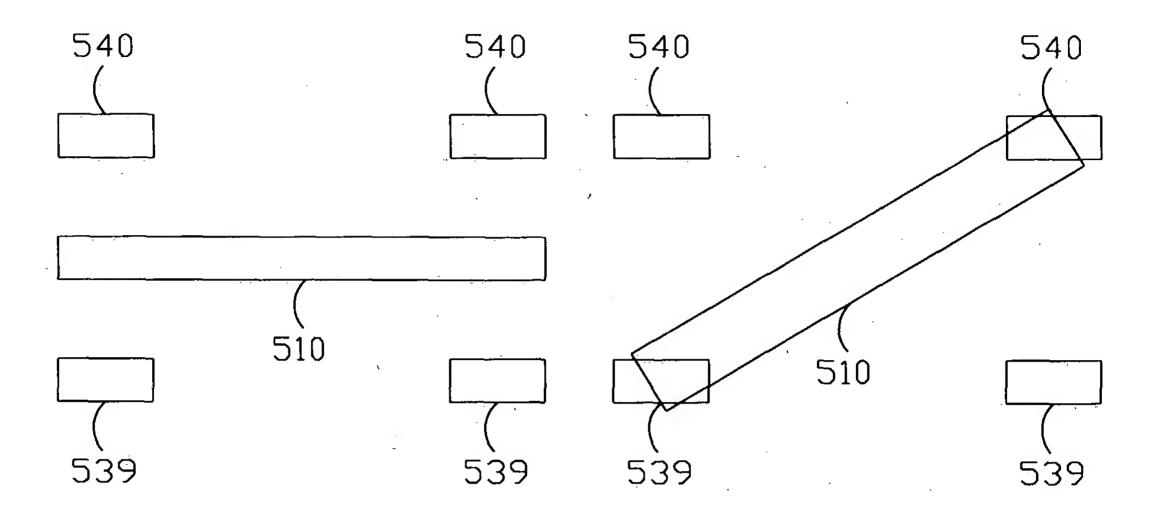


FIG.5A

FIG.5B

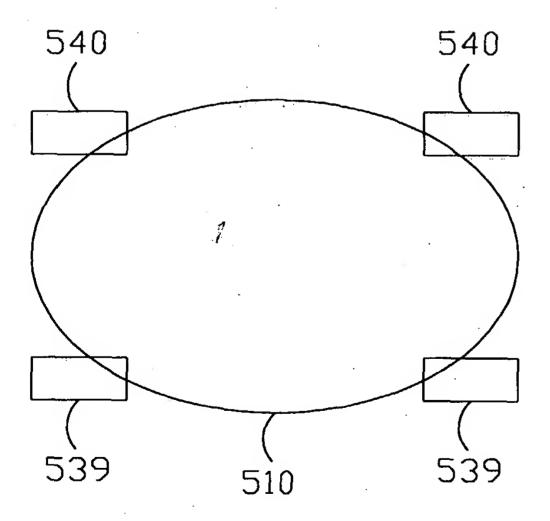


FIG.5C